

Title (en)

Method of manufacturing a substrate for a liquid jet recording head

Title (de)

Methode zur Herstellung eines Substrats für einen Flüssigkeitsstrahl-Aufzeichnungskopf

Title (fr)

Méthode pour fabriquer un substrat pour une tête d'enregistrement à jet liquide

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Application

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Abstract (en)

[origin: EP0559295A1] This specification discloses a method of manufacturing a substrate for an ink jet recording head having an electro-thermal transducer disposed on a substrate supporting member and generating heat energy available to discharge ink. Short-circuited electrode wiring portions (207) are cut with a laser beam. Then a filler (208) and a protective layer (204) are deposited by Laser CVD and sputtering, respectively. The specification also discloses a substrate for an ink jet recording head manufactured by such method, an ink jet recording head formed by the use of such substrate, and an ink jet recording apparatus having the head. <IMAGE>

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